

VERSION WITH MARKINGS TO SHOW CHANGES MADE

Fig. 5 is an exploded view of a proximal portion of the electrosurgical probe;

Fig. 6 is an end view of an exemplary electrode support comprising a multi-layer wafer with plated conductors for electrodes;

Figs. 7 and 8 are side views of the electrode support of Fig. 6;

Figs. 9A-~~12A~~13A are side views of the individual wafer layers of the electrode support;

Figs. 9B-~~12B~~13B cross-sectional views of the individual wafer layers;

Fig. 13 is a side view of an individual wafer layer;

Figs. 14 and 15 illustrate an alternative multi-layer wafer design according to the present invention;

Fig. 16 is a perspective view of an electrosurgical probe having an elongated, blade-like active electrode;

Fig. 17A-17C are cross-sectional views of the distal portions of three different embodiments of an electrosurgical probe according to the present invention;

Fig. 18 illustrates an electrosurgical probe with a 90° distal bend and a lateral fluid lumen;

Fig. 19 illustrates an electrosurgical system with a separate fluid delivery instrument according to the present invention;

Figs. 20A and 20B are cross-sectional and end views, respectively, of yet another electrosurgical probe incorporating flattened active electrodes;

Fig. 21 is a detailed end view of an electrosurgical probe having an elongate, linear array of active electrodes suitable for use in surgical cutting;

Fig. 22 is a detailed view of a single active electrode having a flattened end at its distal tip;

Fig. 23 is a detailed view of a single active electrode having a pointed end at its distal tip;

Fig. 24 is a perspective view of the distal portion of another electrosurgical probe according to the present invention;

Fig. 25 illustrates another embodiment of the probe of the present invention, specifically designed for creating incisions in external skin surfaces;